

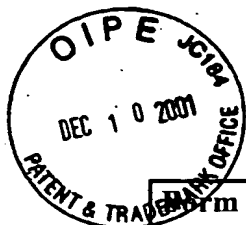


Form 1449 (Modified)	Atty Docket No. KLA1P018	Application No.: 09/894,987
Information Disclosure Statement By Applicant	Applicant: Adel et al.	RECEIVED DEC 12 2001 Technology Center 2600
(Use Several Sheets if Necessary)	Filing Date 06/27/01	

### U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
IK	A	4,475,811	10/09/84	Brunner	355	133	
IK	B	4,538,105	08/27/85	Ausschnitt	324	766	
IK	C	4,703,434	10/27/87	Brunner	716	21	
IK	D	4,714,874	12/22/87	Morris et al.	324	601	
IK	E	4,757,707	07/19/88	Harvey et al.	73	19.07	
IK	F	4,778,275	10/18/88	van den Brink et al.	356	401	
IK	G	4,782,288	11/01/88	Vento	324	765	
IK	H	4,855,253	08/08/89	Weber	438	18	
IK	I	4,929,083	05/29/90	Brunner	356	400	
IK	J	5,017,514	05/21/91	Nishimoto	438	14	
IK	K	5,112,129	05/12/92	Davidson et al.	356	497	
IK	L	5,148,214	09/15/92	Ohta et al.	355	43	
IK	M	5,156,982	10/20/92	Nagoya	438	14	
IK	N	5,216,257	06/01/93	Brueck et al.	250	548	
IK	O	5,262,258	11/16/93	Yanagisawa	430	22	
IK	P	5,296,917	03/22/94	Kusonose et al.	356	401	
IK	Q	5,383,136	01/17/95	Cresswell et al.	702	97	
IK	R	5,436,097	07/25/95	Norishima et al.	430	5	
IK	S	5,438,413	08/01/95	Mazor et al.	356	508	
IK	T	5,479,270	12/26/95	Taylor	358	488	
IK	U	5,498,501	03/12/96	Shimoda et al.	430	22	
IK	V	5,596,413	01/21/97	Stanton et al.	356	401	
IK	W	5,617,340	04/01/97	Cresswell et al.	702	85	
IK	Z	5,627,083	05/06/97	Tounai et al.	438	18	
IK	Y	5,665,495	09/09/97	Hwang	430	5	
IK	Z	5,699,282	12/16/97	Allen et al.	702	85	
Examiner <i>Rupen Kbel</i>				Date Considered <i>6/14/04</i>			

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



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(Use Several Sheets if Necessary)	Filing Date 06/27/01	Group 2621

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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
UR	A1	5,701,013	12/23/97	Hsia et al.	250	491.1	
UR	B1	5,702,567	12/30/97	Mitsui et al.	438	689	
UR	C1	5,703,685	12/30/97	Senda et al.	356	401	
UR	D1	5,712,707	01/27/98	Ausschnitt et al.	356	401	
UR	E1	5,757,507	05/26/98	Ausschnitt et al.	356	401	
UR	F1	5,766,809	06/16/98	Bae	430	22	
UR	G1	5,783,342	07/21/98	Yamashita et al.	430	30	
UR	H1	5,805,290	09/08/98	Ausschnitt et al.	356	401	
UR	I1	5,835,196	11/10/98	Jackson	355	53	
UR	J1	5,841,144	11/24/98	Cresswell	Withdrawn		
UR	K1	5,857,258	01/12/99	Penzes et al.	29	846	
UR	L1	5,872,042	02/16/99	Hsu et al.	438	401	
UR	M1	5,877,036	03/02/99	Kawai	438	16	
UR	N1	5,877,861	03/02/99	Ausschnitt et al.	356	401	
UR	O1	5,902,703	05/11/99	Leroux et al.	430	5	
UR	P1	5,912,983	06/15/99	Hiratsuka	382	144	
UR	Q1	5,923,041	07/13/99	Cresswell et al.	250	491.1	
UR	R1	5,939,226	08/17/99	Tomimatu	430	5	
UR	S1	5,949,145	09/07/99	Komuro	257	797	
UR	T1	5,968,693	10/19/99	Adams	430	30	
UR	U1	6,023,338	02/08/00	Bareket	356	401	
UR	V1	6,077,756	06/20/00	Lin et al.	438	401	
UR	W1	6,079,256	06/27/00	Bareket	73	103	
UR	X1	6,118,185	09/12/00	Chen et al.	257	797	
UR	Y1	6,128,089	10/03/00	Ausschnitt et al.	356	401	
UR	Z1	6,130,750	10/10/00	Ausschnitt et al.	356	401	
Examiner <i>Vynne Klee</i>				Date Considered <i>6/14/04</i>			

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



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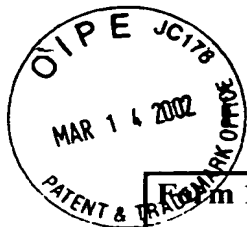
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**U.S. Patent Documents**

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub- class	Filing Date
W	A2	6,137,578	10/24/00	Ausschnitt	356	399	
W	B2	6,140,217	10/31/00	Jones et al.	438	597	
W	C2	6,146,910	11/14/00	Cresswell et al.	438	14	
W	D2	6,160,622	12/12/00	Dirksen et al.	356	401	
W	E2	6,165,656	12/26/00	Tomimatu	430	22	
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Examiner <i>Kyran Klen</i>	Date Considered <i>6/14/04</i>
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<b>Form 1449 (Modified)</b>  <b>Information Disclosure Statement By Applicant</b>  (Use Several Sheets if Necessary)	Atty Docket No. KLA1P018	Application No.: 09/894,987
	Applicant: Adel et al. Filing Date June 27, 2001	Group 2621

### U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
<i>UK</i>	A	5,841,144	11/24/98	Cresswell	<i>withdrawn</i>		
<i>UK</i>	B	5,172,190	12/15/92	Kaiser	356	401	
<i>UK</i>	C	4,820,055	04/11/89	Müller	356	401	
<i>UK</i>	D	6,084,679	07/04/00	Steffan et al.	356	401	
<i>UK</i>	E	6,079,256	06/27/00	Bareket	73	105	
	F						
	G						
	H						
	I						

### Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
<i>UK</i>	J	0947828	06.10.99	EP				
<i>UK</i>	K	0818814	14.01.98	EP				
	L							
	M							
	N							

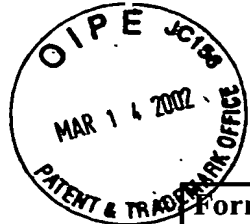
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### Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication	Technology Center 2600
	O		
	P		
	Q		
Examiner <i>Vyvan Klee</i>	Date Considered <i>6/14/04</i>		

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Form 1449 (Modified)	Atty Docket No. KLA1P018	Application No.: 09/894,987
<b>Information Disclosure Statement By Applicant</b>	Applicant: Adel et al.	
(Use Several Sheets if Necessary)	Filing Date June 27, 2001	Group 2621

#### U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
<i>ue</i>	A	4,757,207	07/12/88	Chappelow et al.	250	491.1	
<i>ue</i>	B	5,414,514	05/09/95	Smith et al.	356	509	
<i>ue</i>	C	5,477,057	12/19/95	Angeley et al.	250	548	
<i>ue</i>	D	6,020,966	02/01/00	Ausschnitt et al.	356	369	
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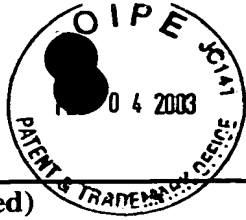
#### Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J							
	K							
	L							
	M							
	N							

#### Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
<i>ue</i>	O	Levinson, "Lithography Process Control", Tutorial Texts in Optical Engineering, Volume TT28, Chapter 5, pages 96 - 107.
<i>ue</i>	P	Rivera et al., "Overlay Performance on Tungsten CMP Layers Using the ATHENA Alignment System".
<i>ue</i>	Q	Hsu et al., "Characterizing lens distortion to overlay accuracy by using fine measurement pattern", March 1999, SPIE Vol. 3677.
Examiner <i>Vijay K. K.</i>		Date Considered <i>6/14/01</i>

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



<b>Form 1449 (Modified)</b>  <b>Information Disclosure Statement By Applicant</b>  (Use Several Sheets if Necessary)	Atty Docket No. KLA1P018	Application No.: 09/894,987
	Applicant: Adel et al.	Group 2621
	Filing Date June 27, 2001	

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#### U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
uc	A	4,251,160	02/17/81	Bouwhuis et al.	356	401	
uc	B	5,100,237	03/31/92	Wittekoek et al.	356	401	
la	C	5,481,362	01/02/96	Van Den Brink et al.	356	401	
uc	D	6,384,899	05/07/02	den Boef	355	69	
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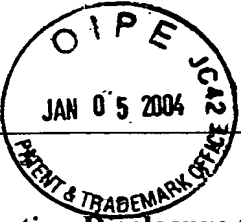
#### Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J							
	K							
	L							
	M							
	N							

#### Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
uc	O	Monshouwer et al., "Method of Measuring Overlay", June 27, 2002, U.S. Patent Application Publication.
	P	
	Q	
Examiner <i>Vignee Klee</i>		Date Considered <i>6/14/04</i>

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

PTO-1449		Application No.	Applicant(s)	
		09/895,647	Erin M. Defossé, et al.	
<b>Information Disclosure Citation in an Application</b>		Docket Number	Group Art Unit	Filing Date
		064814.0193	2635	June 29, 2001

## U.S. PATENT DOCUMENTS

		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
<i>we</i>	A.	6385772 B1	05/07/2002	Courtney	725	105	04/15/1999
	B.						
	C.						
	D.						
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	I.						

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## FOREIGN PATENT DOCUMENTS

		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	J.							
	K.							
	L.							

## NON-PATENT DOCUMENTS

		DOCUMENT (Including Author, Title, Source, and Pertinent Pages)	DATE
	M.		
	N.		
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	Q.		
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EXAMINER <i>Vincent K. Chen</i>	DATE CONSIDERED <i>6/14/04</i>
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.